

Supporting Information

Bandgap widening through doping for improving the photocatalytic oxidation ability of narrow-gap semiconductors

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Supporting information note

Note 1. La atom doping position

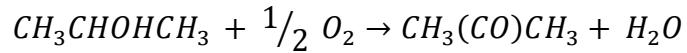
In the 12.5 at% La-BiVO₄, two Bi sites would be selected for La atom doping, so 15 kinds of combinations are available. The interatomic distances of these choices are listed in figure S1. The nearest interatomic distance of the Bi site is 3.76 Å, and the farthest one is 7.25 Å. Structure models with different doping pattern were calculated to discuss how La dopant distribution would influence the result. The nearest, the midst, and the farthest doping choice were selected for calculation (figure S2, S3, and S4 for their crystal structure). The calculation results are listed in table S1.

From Table S1, it can be seen that compared to the nearest and midst La doping choice, the total energy for the farthest La doping choice was 0.02 eV higher. Generally, higher energy indicates instability. However, in the current case, the energy difference is negligible as it is inside the error bar range of the calculation method^{1,2}. On top of that, both the nearest La doping case and the midst doping case present the identical CB and VB position with 6.25 at% La-BiVO₄. We suspect that the localized La atoms would behave like the model with lower doping concentration.

In the current study, we adopted the distant La doping model for 12.5 at% La-BiVO₄ to discuss the effect caused by homogeneous La doping.

Note 2. IPA to acetone conversion reaction

The IPA to acetone conversion has been well investigated by previous research³. The chemical equation is described below



Note 3. Calculation detail of Bi to O bonding length in table S3

In BiVO₄, each Bi atom is surrounded by 8 O atoms. The average Bi to O distance is calculated from every Bi to its surrounding 8 O atoms' bonding length.

Note 4. Rietveld analysis of XRD pattern.

We conducted Rietveld analysis of XRD pattern through Fullprof⁴ to evaluate the structure difference of pristine BiVO₄ and La-BiVO₄ obtained experimentally. The refinement starts with the scheelite monoclinic BiVO₄ reported from literature⁵. The Rietveld analysis result of pristine BiVO₄ and 10 at% La-BiVO₄ are shown in Figure S9 and Figure S10, respectively.

In a Rietveld analysis, the weighted profile factor (Rwp) measures the agreement between the reflection intensity calculated from a crystallographic model and those measured experimentally. And the Bragg R-factor depends on the fitting of the structure parameters rather than the profile parameters. In our Rietveld analysis, the Rwp value reached 10.1 % and 11.6 % for pristine BiVO₄ and 10 at% La-BiVO₄, respectively. Moreover, the Bragg R-factor reaches 7.33 % and 3.65 % for pristine BiVO₄ and 10 at% La-BiVO₄, respectively, indicating a good fitting of structural

parameters. The structural parameters of the experimentally synthesized materials are listed in table S6.

Note 5. Tauc plot calculation

The bandgap of BiVO₄ and La-BiVO₄ was calculated using Tauc plots with $h\nu$ as the x-axis, and $(\alpha h\nu)^{1/r}$ as the y axis, where h , ν , and α represent the Planck constant, the frequency of light, and the Kubelka- Munk value obtained from UV-Vis spectra, respectively. The value of r is determined by the semiconductors' property: for direct bandgap semiconductors, r is 1/2, while for indirect bandgap semiconductors, r is 2. According to the previous research⁶, BiVO₄ is a direct bandgap semiconductor, so we use $r = \frac{1}{2}$ for tauc plot calculation.

Note 6. Internal quantum efficiency calculation

The absorbed photon number was calculated using the following equation:

$$N_{ads_{photon}}(mol) = \frac{1}{N_A} \int_{300\ nm}^{800\ nm} \frac{\lambda P(\lambda) SR(\lambda)}{hc} \left(\frac{l'}{l}\right) d\lambda$$

In which:

- λ refers to wavelength.

- $P(\lambda)$ refers to the spectral power density distribution measured by USHIO USR-45 spectroradiometer.

- S refers to the irradiation area of the photocatalyst.

- $R(\lambda)$ represents the reflection ratio measured by UV-Vis spectroscopy of the material.

h , c and N_A are Planck constant, light velocity and Avogadro number, respectively.

The internal quantum yield was calculated using the following equation

$$\Phi = \frac{n_{acetone}}{N_{ads\ photon}} \times 100\%$$

In which $n_{acetone}$ is the amount of acetone molecules, $N_{ads\ photon}$ is the adsorbed photon number.

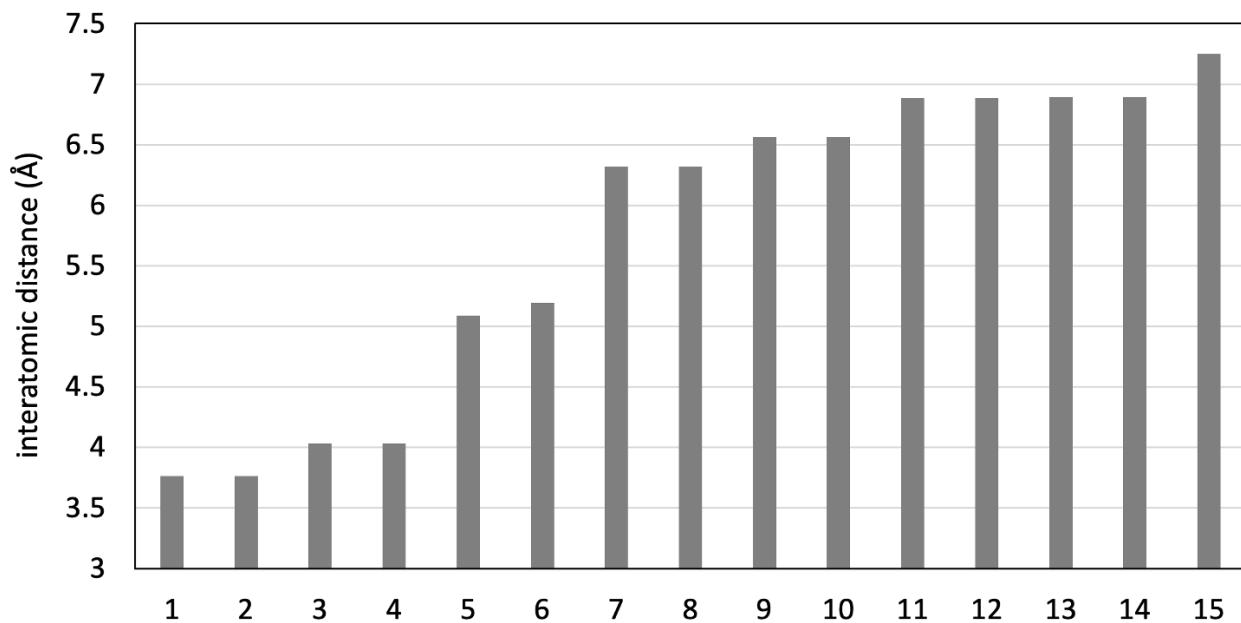


Figure S1 The interatomic distances of the two different Bi sites in BiVO_4 supercell.

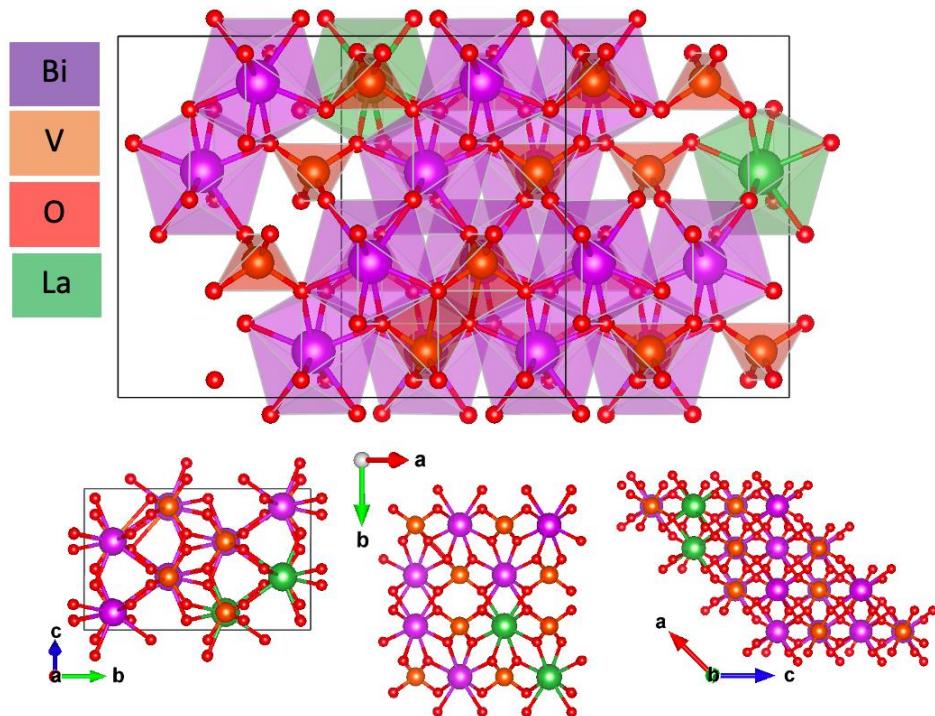


Figure S2 The structure of the 12.5 at% La-BiVO₄ with nearest La doping choice.

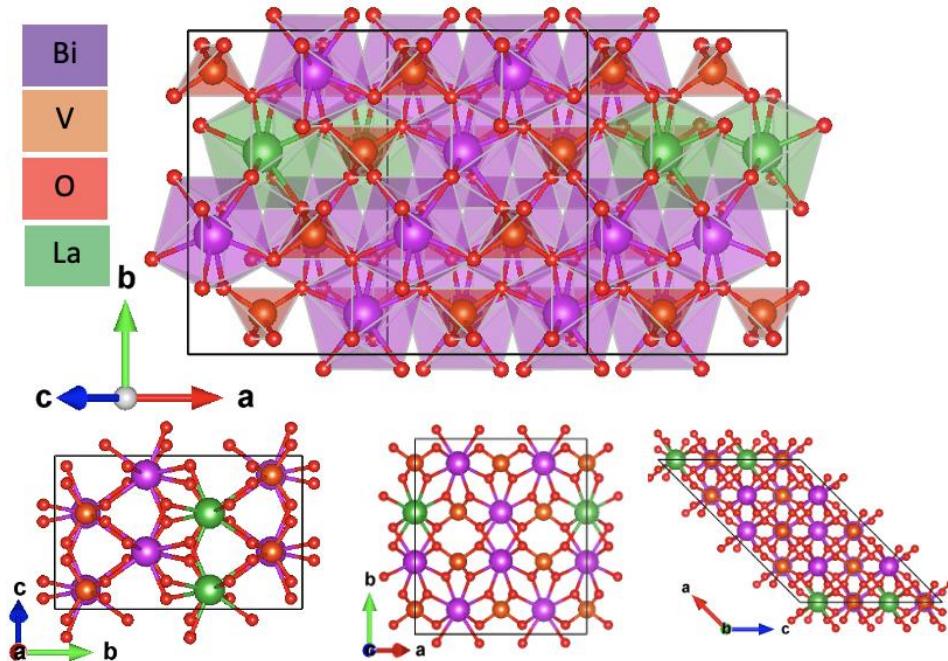


Figure S3 The structure of the 12.5 at% La-BiVO₄ with midst La doping choice.

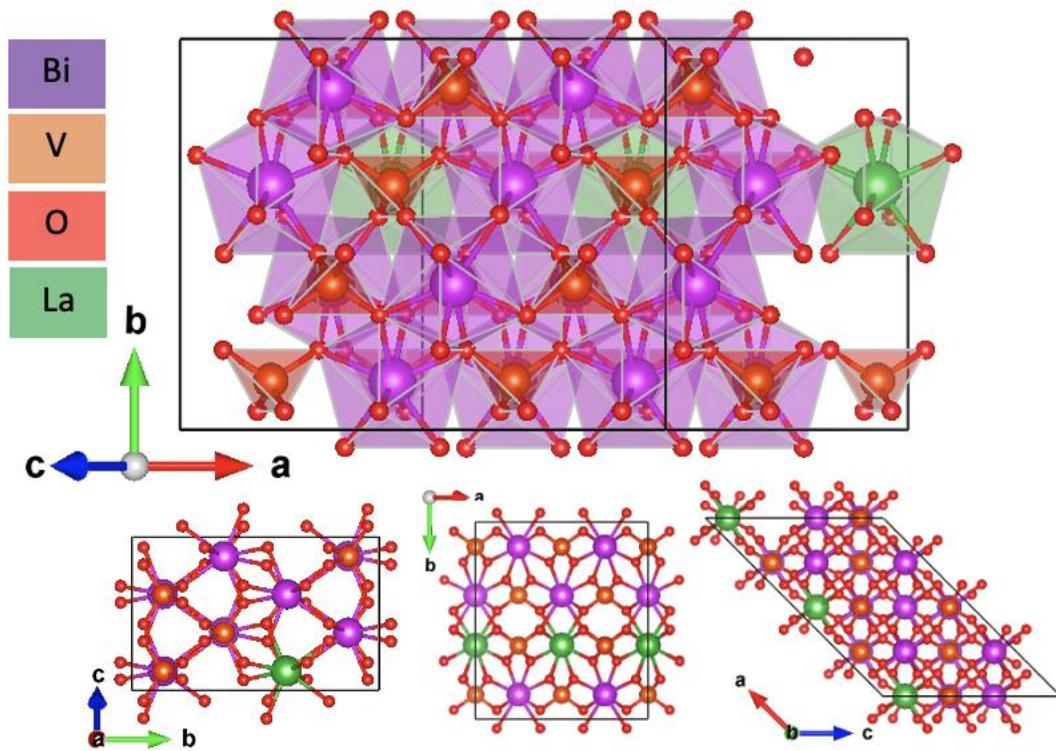


Figure S4 The structure of the 12.5 at% La-BiVO₄ with farthest La doping choice.

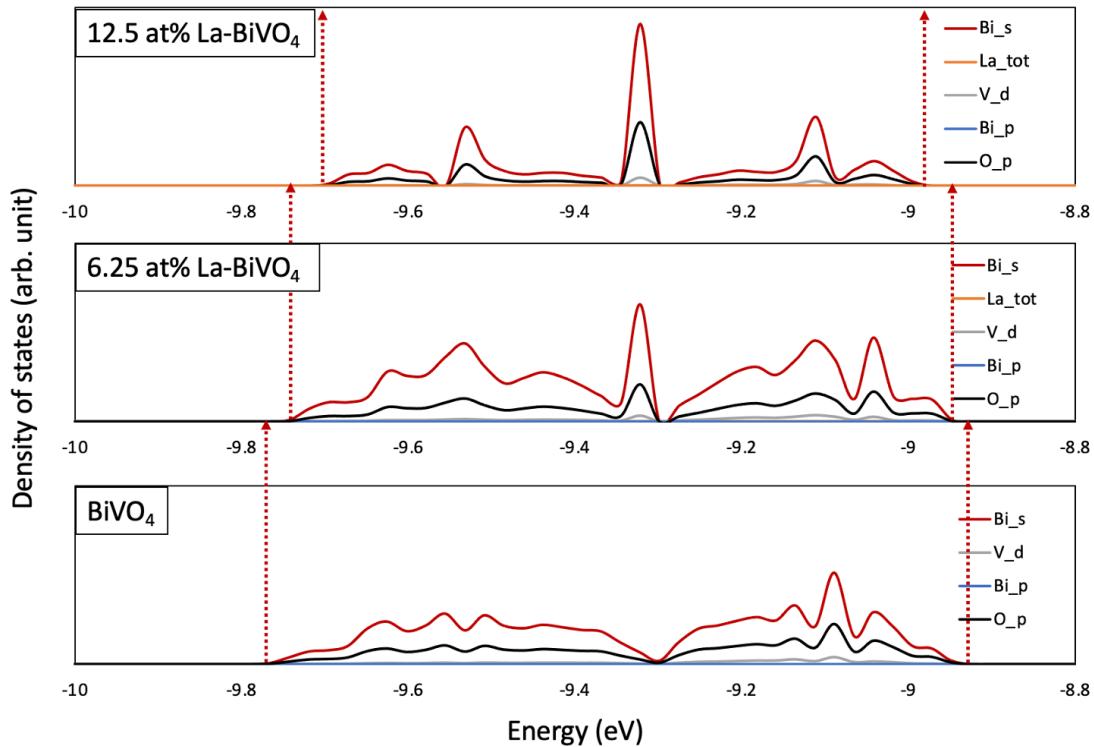


Figure S5 Enlarged DOS which mainly comprised the Bi s and O p orbitals. (The red line represents the Bi s orbitals, the black line represents the O p orbitals, V d orbital, Bi p orbital and La electronic contribution are shown by grey, blue and orange line respectively.)

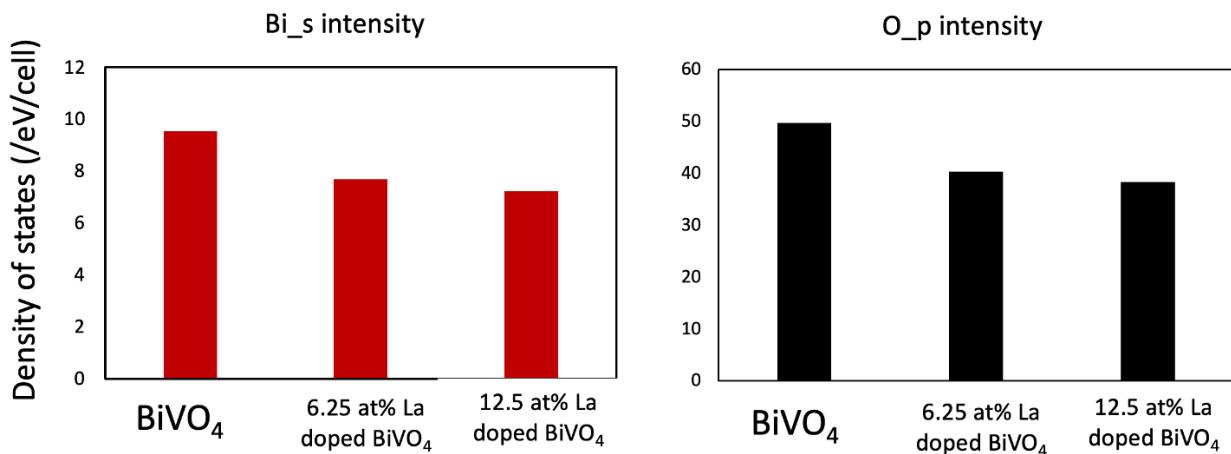


Figure S6 Intensity of Bi s and O p orbitals formed at the VB top of different structures.

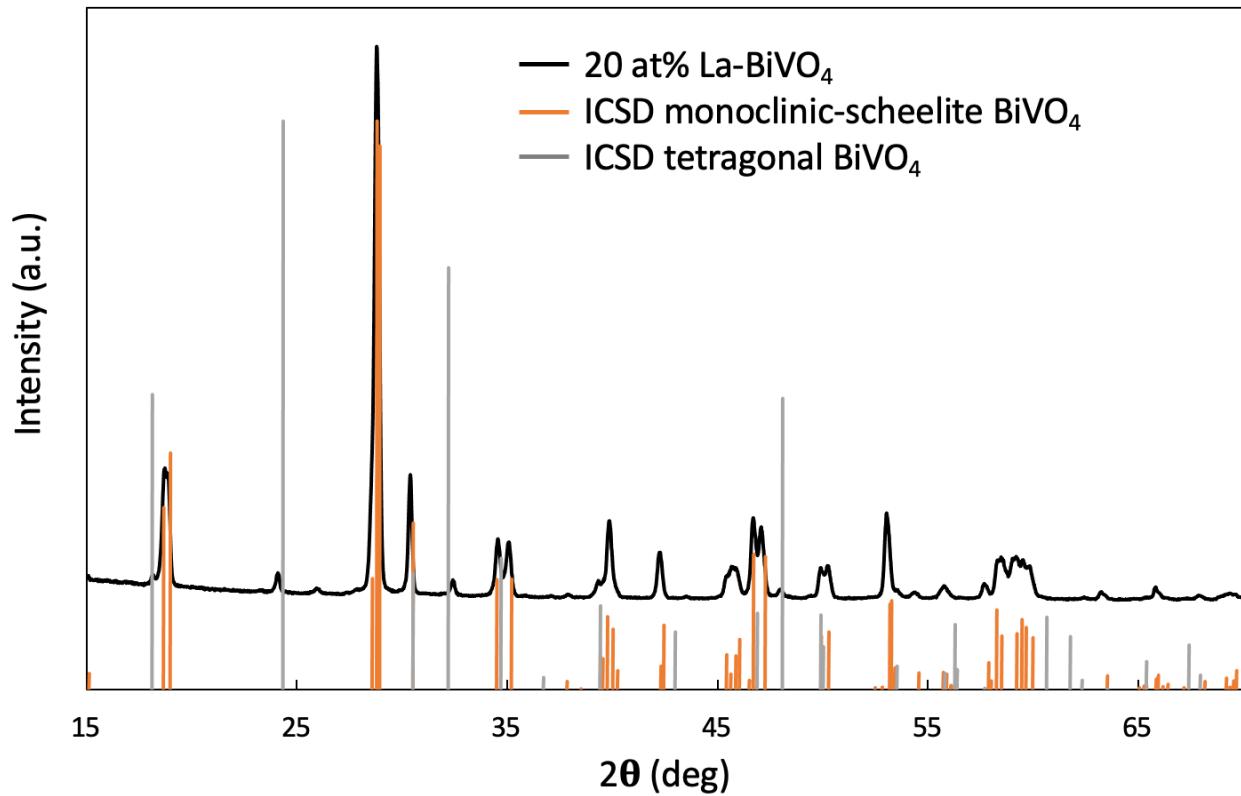


Figure S7 XRD pattern of 20 at% La-BiVO₄, both monoclinic and tetragonal phases exist in the material.

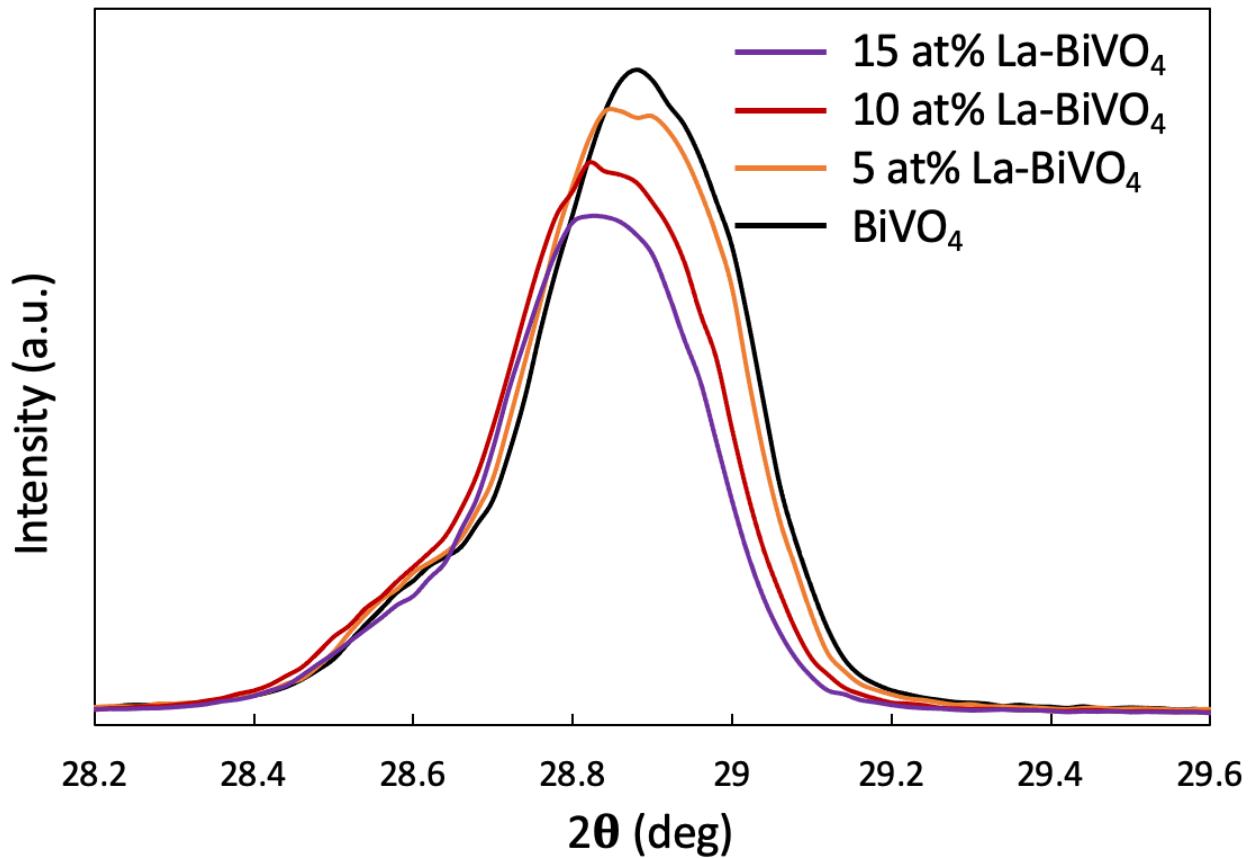


Figure S8 Comparison of XRD peak intensity of pristine and La-BiVO_4 .

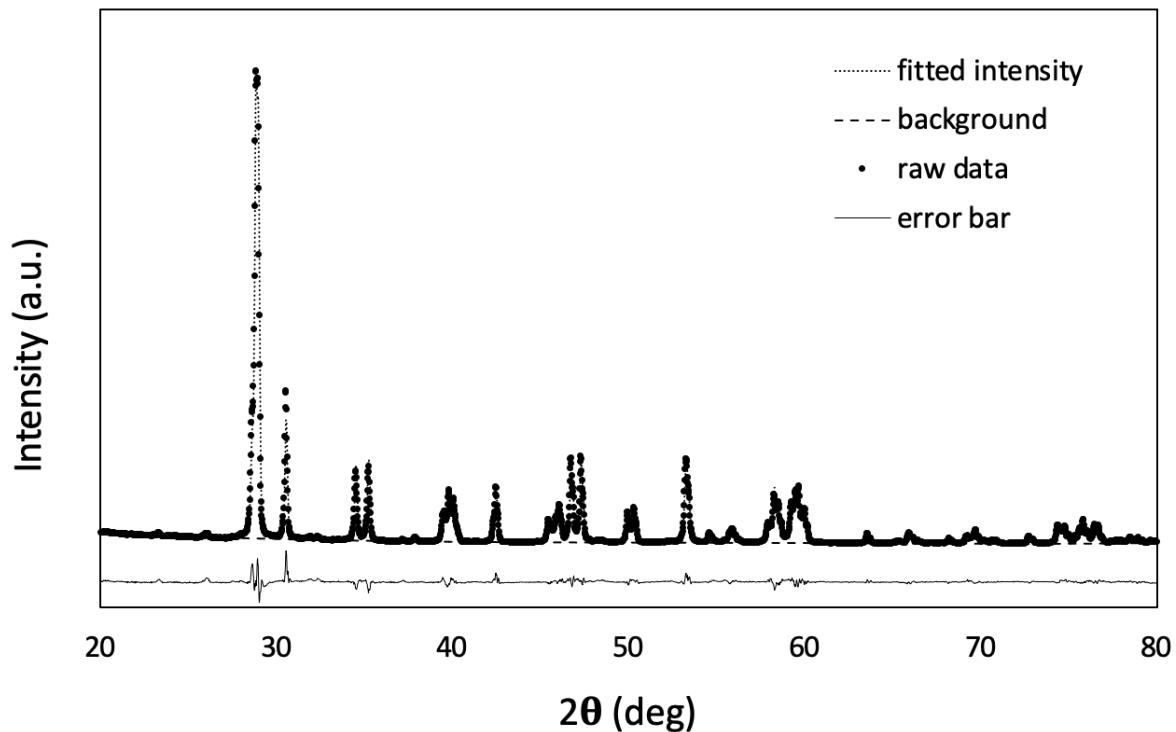


Figure S9 Rietveld analysis result of the pristine BiVO_4

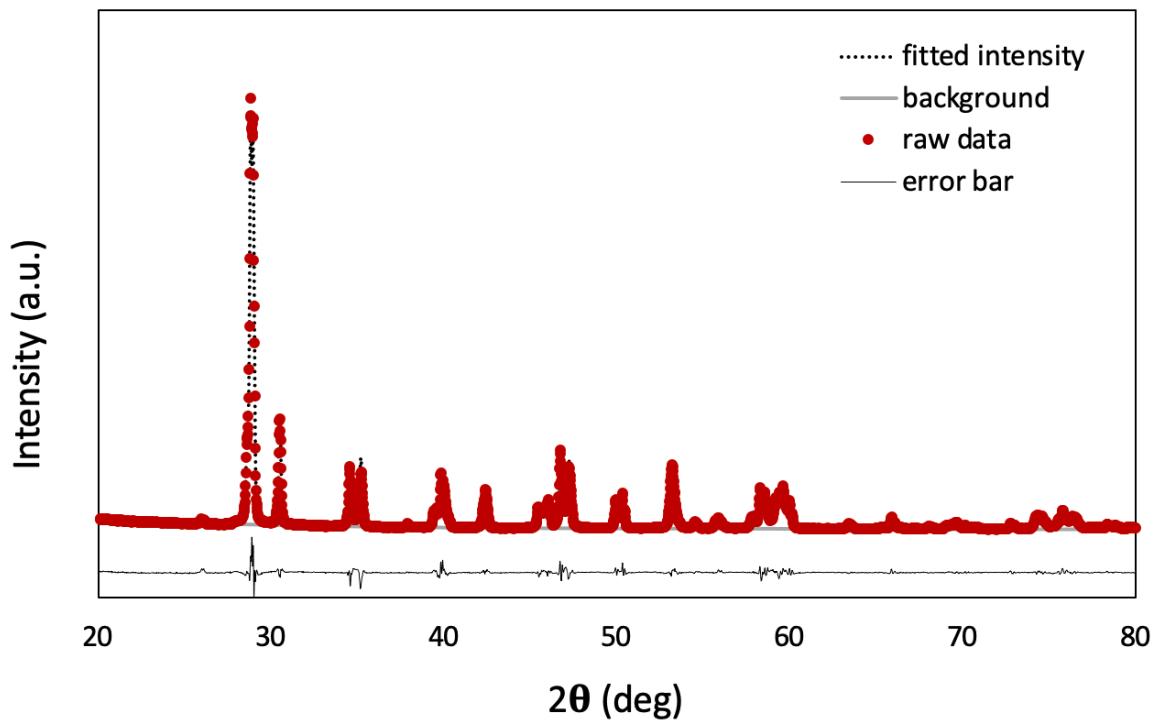


Figure S10 Rietveld analysis result of the 10 at% La- BiVO_4

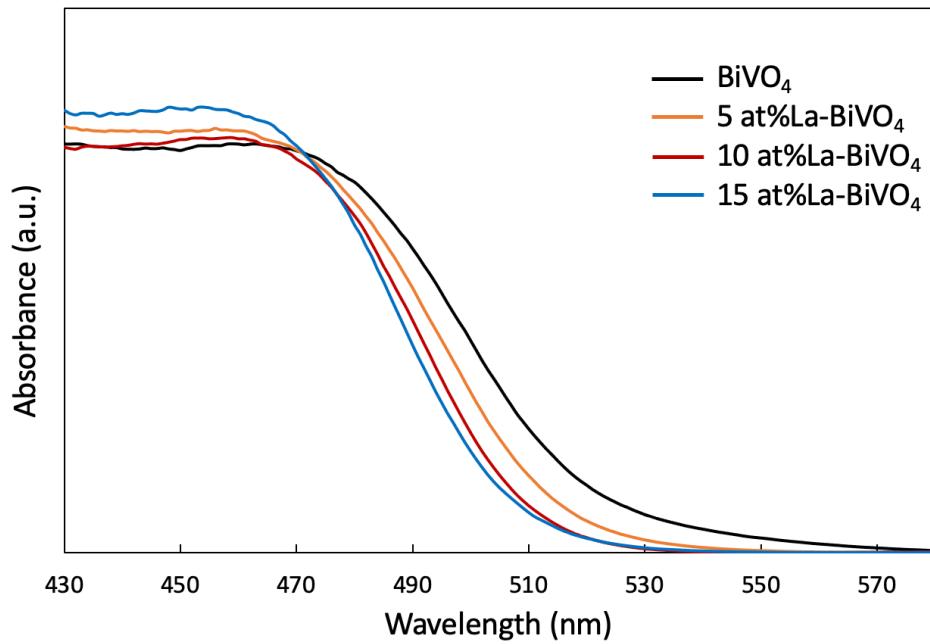


Figure S11 UV-Vis light absorption spectra of pristine BiVO_4 and La-BiVO_4 .

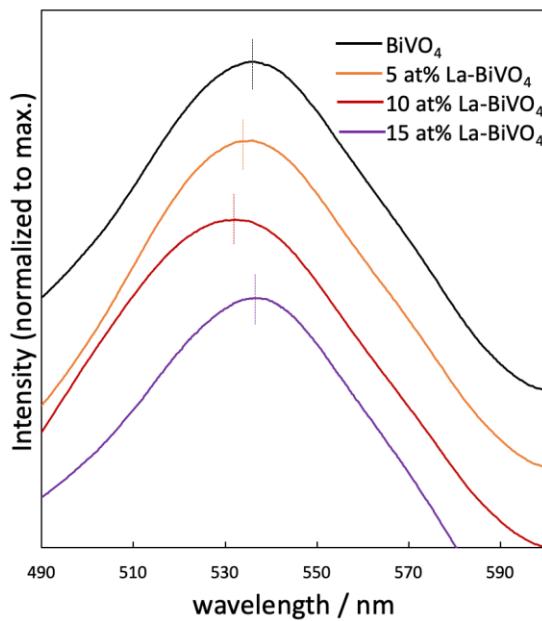


Figure S12 Photoluminescence spectra with an excitation wavelength at 355 nm for the pristine BiVO_4 , 5 at% La-BiVO_4 , 10 at% La-BiVO_4 , and 15 at% La-BiVO_4 , respectively. The peak intensity were normalized to the maximum intensity to show the gradual shift in emission peak wavelength.

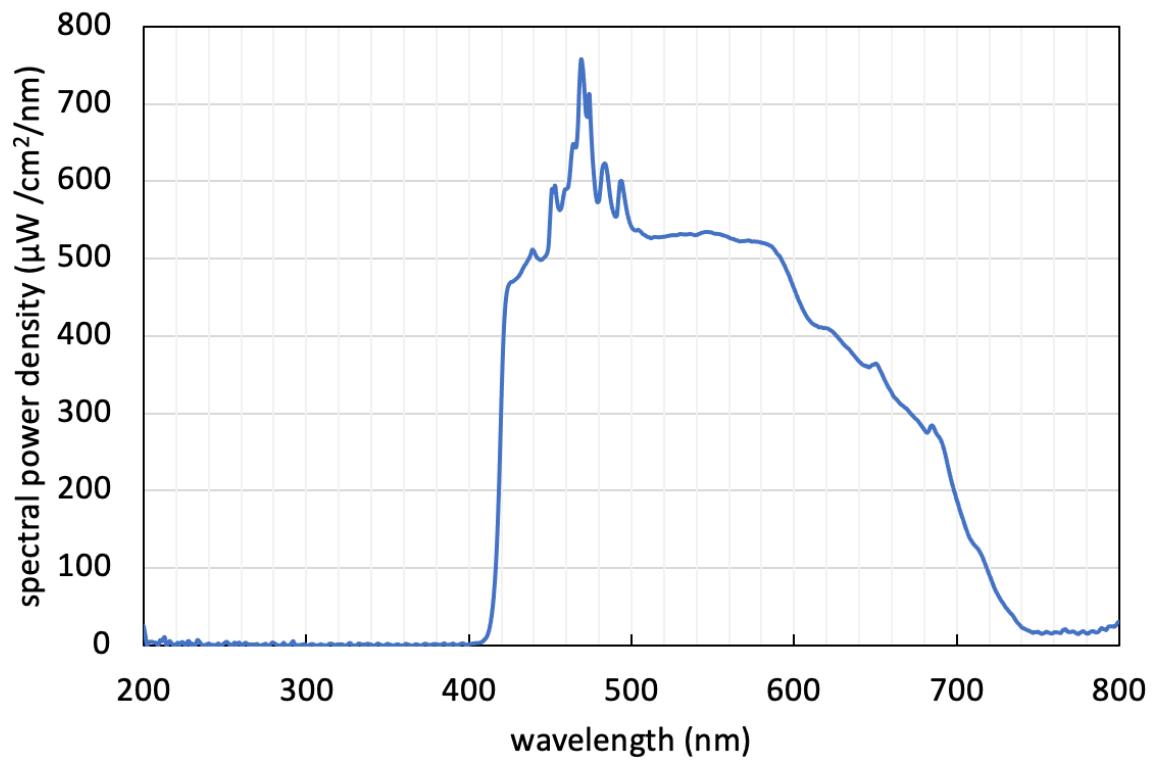


Figure S13 Spectra of xenon lamp equipped with a 422 nm cutoff filter.

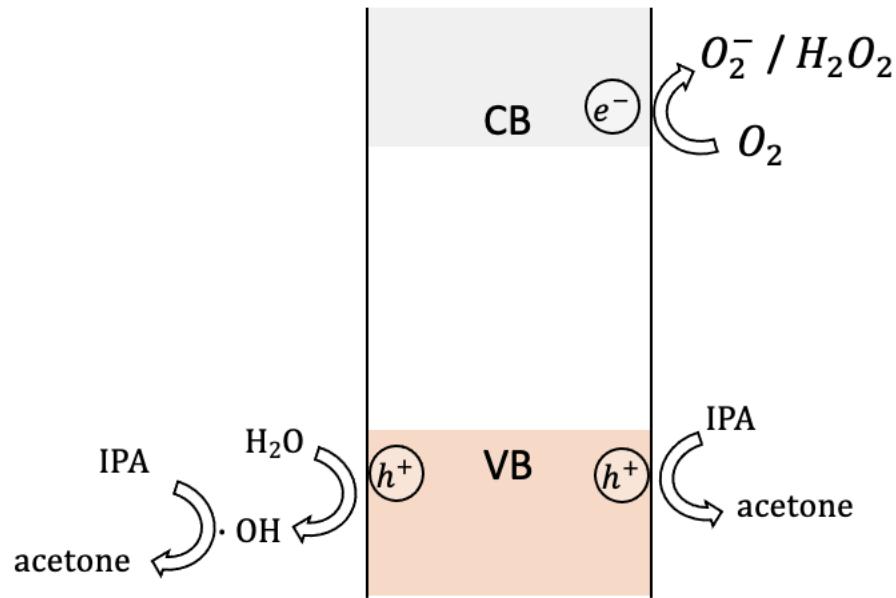


Figure S14 Schematic illustration for the photocatalytic oxidation of 2-propanol to acetone over La-BiVO₄

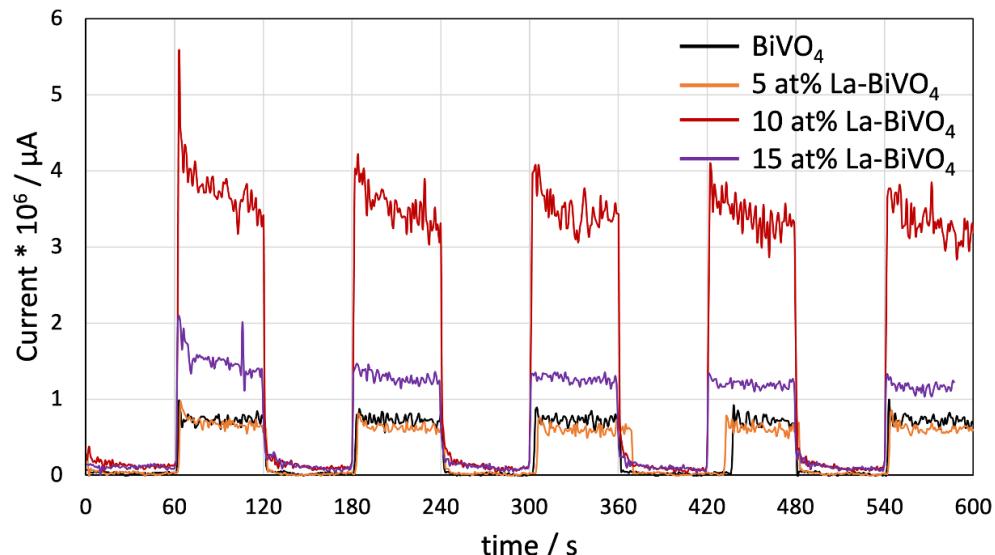


Figure S15 Photocurrent properties of BiVO₄ and La doped BiVO₄ electrodes under a Xe lamp irradiation passed through a 450 nm bandpass filter with the bias potential of 1.23 V vs RHE.

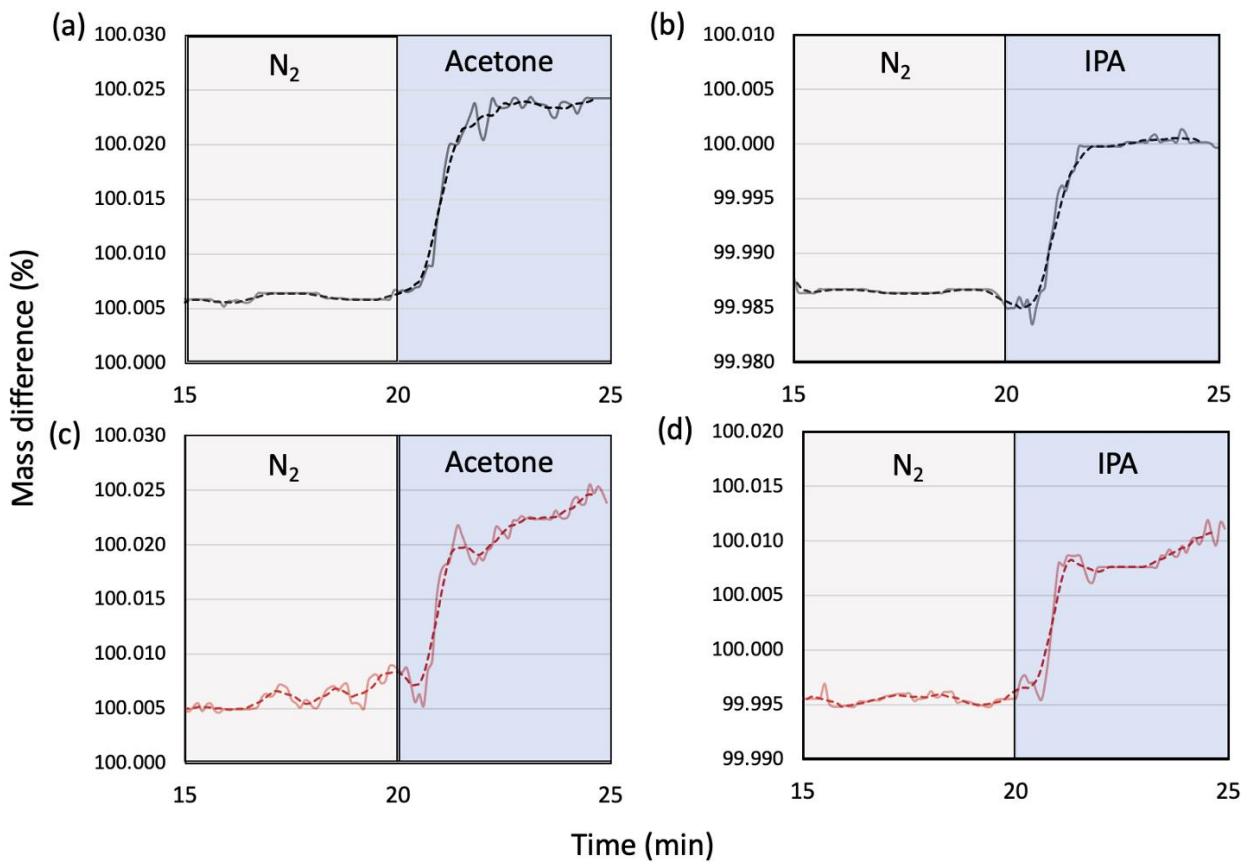


Figure S16 Gaseous acetone and IPA adsorption property over BiVO_4 and 10 at% La- BiVO_4 . Figure (a) and (b) represent the acetone and IPA adsorption property over pristine BiVO_4 , respectively. Figure (c) and (d) represent the acetone and IPA adsorption property over 10 at% La- BiVO_4 , respectively.

We compared the gaseous acetone and IPA adsorption property through TG-DTA analysis. We kept the temperature at 25 °C during the analysis since it is the condition that we used for activity evolution.

Nitrogen was purged for the initial 20 minutes, then IPA or acetone gas was purged continuously for 5 min. The mass difference during the targeted gas purging process was recorded, as summarized in table S9.

Table S1 Calculation result of 12.5 at% La-BiVO₄ with different doping position choices.

Structure	interatomic distance of La (after ionic relaxation)	CB (eV)	VB (eV)	Bandgap (eV)	Total Energy (eV)
farthest La	7.31 Å	2.049	-0.075	2.124	-722.06
midst La	5.17 Å	2.049	-0.052	2.101	-722.08
nearest La	3.96 Å	2.049	-0.052	2.101	-722.08

Table S2 Structural parameters of each optimized structure obtained after ionic relaxation step.

Structure name	BiVO ₄	6.25 at% La-BiVO ₄	12.5 at% La-BiVO ₄
$2 \times a$ (Å)	14.60532	14.61680	14.62336
b (Å)	11.74568	11.76554	11.78549
$2 \times c$ (Å)	10.31987	10.33069	10.33069
β (°)	134.9224	134.9494	134.8804

Table S3 Average Bi to O bonding length in different structures

Structure name	Average Bi to O bonding length (Å)
Pristine BiVO ₄	2.471
6.25 at% La-BiVO ₄	2.473
12.5 at% La-BiVO ₄	2.475

Table S4 Bandwidth of the DOS shown in Figure S5.

Structure name	Bandwidth (eV)
Pristine BiVO ₄	0.87
6.25 at% La-BiVO ₄	0.79
12.5 at% La-BiVO ₄	0.73

Table S5 Full width at half maximum (FWHM) of the XRD peak described in Figure S8

sample	FWHM (2theta/rad)
BiVO ₄	0.29
5 at% La-BiVO ₄	0.30
10 at% La-BiVO ₄	0.32
15 at% La-BiVO ₄	0.30

Table S6 Structural parameters of pristine BiVO₄ and La-BiVO₄ obtained from Rietveld analysis

Structure name	Pristine BiVO ₄	10 at% La-BiVO ₄
a	7.25155	7.25192
b	11.70300	11.72590
c	5.09299	5.10022
β	134.227	134.296
volume	309.718208	310.416126

Table S7 ICP analysis result of La-BiVO₄, weight ratios, and atomic ratios of La to Bi.

Structure name	element	Weight percent	Atomic percent
5 at% La-BiVO ₄	Lanthanum	2.2 %	5.1 %
	Bismuth	61 %	95 %
10 at% La-BiVO ₄	Lanthanum	4.6 %	10.4 %
	Bismuth	59.1 %	90 %
15 at% La-BiVO ₄	Lanthanum	6.7 %	15.4 %
	Bismuth	55.1 %	85 %

Table S8 Binding energy of each orbital obtained from HAXPES.

Sample name	La 3d _{5/2}	Bi 4f _{7/2}	V 2p _{3/2}	O 1s
BiVO ₄		159.45 eV	517.15 eV	530.4 eV
5 at% La-BiVO ₄	834.95 eV	159.45 eV	517.15 eV	530.4 eV
10 at% La-BiVO ₄	834.95 eV	159.55 eV	517.25 eV	530.5 eV
15 at% La-BiVO ₄	834.95 eV	159.55 eV	517.25 eV	530.5 eV

Table S9 Mass difference of IPA and acetone over pristine BiVO₄ and 10 at% La-BiVO₄ respectively.

Sample	Mass difference of acetone	Mass difference of IPA
BiVO ₄	0.02 %	0.015 %
10 at% La-BiVO ₄	0.02 %	0.015 %

Table S10 surface area of pristine BiVO₄ and La-BiVO₄

Sample	Surface area (m ² /g)
BiVO ₄	0.6651
5 at% La-BiVO ₄	0.4147
10 at% La-BiVO ₄	0.3876
15 at% La-BiVO ₄	0.7952

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